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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/788,365	02/21/2001	Tuqiang Ni	015290-517	3359
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Peter K. Skiff BURNS, DOANE, SWECKER & MATHIS, L.L.P. P.O. Box 1404			EXAMINER	
			ZERVIGON, RUDY	
Alexandria, V	A 22313-1404		ART UNIT	PAPER NUMBER
			1763	,
			DATE MAILED: 02/24/2003	

Please find below and/or attached an Office communication concerning this application or proceeding.

		Application No.	Applicant(s)
Office Andien Country		09/788,365	NI ET AL.
·	Office Action Summary	Examiner	Art Unit
<u> </u>	<u> </u>	Rudy Zervigon	1763
Ti Period for R	he MAILING DATE of this communication app eply	ears on the cover sheet with the c	orrespondence address
THE MAI - Extension after SIX (- If the peric - If NO peric - Failure to - Any reply	TENED STATUTORY PERIOD FOR REPLY LING DATE OF THIS COMMUNICATION. s of time may be available under the provisions of 37 CFR 1.13 (6) MONTHS from the mailing date of this communication. So do for reply specified above is less than thirty (30) days, a reply of for reply is specified above, the maximum statutory period we reply within the set or extended period for reply will, by statute, received by the Office later than three months after the mailing tent term adjustment. See 37 CFR 1.704(b).	86(a). In no event, however, may a reply be time within the statutory minimum of thirty (30) days fill apply and will expire SIX (6) MONTHS from cause the application to become ABANDONE	nely filed s will be considered timely. the mailing date of this communication. D (35 U.S.C. § 133).
	esponsive to communication(s) filed on 10 E	<u> Pecember 2002</u> .	
·		s action is non-final.	
	nce this application is in condition for allowa	nce except for formal matters, pr	osecution as to the merits is
	osed in accordance with the practice under t		
4)⊠ Cla	nim(s) <u>25 and 28-40</u> is/are pending in the ap	pplication.	
4a)	Of the above claim(s) is/are withdraw	n from consideration.	
5)∏ Cla	aim(s) is/are allowed.		• .
6)⊠ Cla	im(s) <u>25 and 28-40</u> is/are rejected.	•	
7) Cla	nim(s) is/âre objected to.		
8)∏ Cla	aim(s) are subject to restriction and/or	election requirement.	
Application	Papers		
9) <u></u> The	specification is objected to by the Examiner		
10) <u></u> The	drawing(s) filed on is/are: a)□ accep	ted or b)⊡ objected to by the Exar	miner.
	pplicant may not request that any objection to the		
11) <u></u> The	proposed drawing correction filed on	is: a)☐ approved b)☐ disappro	ved by the Examiner.
·	approved, corrected drawings are required in rep		
12)∐ The	oath or declaration is objected to by the Exa	aminer.	
Priority und	er 35 U.S.C. §§ 119 and 120		
13)∏ Ac	knowledgment is made of a claim for foreign	priority under 35 U.S.C. § 119(a)-(d) or (f).
a)	All b)☐ Some * c)☐ None of:		
1.[Certified copies of the priority documents	s have been received.	en de la companya de Historia
2.[Certified copies of the priority documents	s have been received in Application	on No
3.[* See	Copies of the certified copies of the prior application from the International Burthe attached detailed Office action for a list	eau (PCT Rule 17.2(a)).	-
14)∐ Ackr	nowledgment is made of a claim for domestic	c priority under 35 U.S.C. § 119(e	e) (to a provisional application).
	The translation of the foreign language pro nowledgment is made of a claim for domesti	* •	•
Attachment(s)			· .
2) D Notice of	References Cited (PTO-892) Draftsperson's Patent Drawing Review (PTO-948) on Disclosure Statement(s) (PTO-1449) Paper No(s)	_	Patent Application (PTO-152)
S. Patent and Tradem	ark Office	<u>-</u>	*

Application/Control Number: 09/788,365

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DETAILED ACTION

Claim Rejections - 35 USC § 103

1. The text of those sections of Title 35, U.S. Code not included in this action can be found in a prior Office action.

2. Claims 25, 29, 33, 34, 37, 38 are rejected under 35 U.S.C. 103(a) as being unpatentable

over Ishii (USPat. 5,685,942) in view of Li et al (USPat. 5,772,771).

Ishii teaches a gas injector (85, Figure 4) supplying process gas into a plasma processing

chamber (82; column 7, line 63 - column 8, line 22) wherein a semiconductor substrate ("W") is

subject to plasma processing (column 3, lines 28-50). The gas injector further comprises a gas

injector body (85, Figure 4) sized to extend through a chamber wall (83) of the processing

chamber. As shown in Figure 4, the axial planar distal end surface (surface containing ports 87)

of the gas injector body is exposed within the processing chamber. Figure 4 shows that the gas

injector body includes a plurality of gas outlets (87) adapted to supply process gas into the

processing chamber.

Figure 4 shows that the gas outlets of the gas injector body (85, Figure 4) are located at an axial

end surface (surface containing ports 87) of the gas injector body. The gas outlets further

including a center gas outlet (center portion 87) extending in the axial direction and a plurality of

parallel outlets extending at a common angle to the axial direction, wherein the gas outlets are

located are located in the axial distal end surface of the gas injector body.

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Ishii further teaches that the gas injector includes a planar axial end surface (surface containing

ports 87; Figure 4) that is flush with an interior surface of a dielectric window (83; "insulating

material"; column 8, line 7) forming a chamber wall. Ishii also teaches a surface (flange portion

of 85, Figure 4) adapted to overlie an outer surface of the chamber wall.

Ishii does not teach gas outlets further including a plurality of angled gas outlets extending at an

acute angle to the axial direction.

Li teaches a gas injector (Figure 1A) supplying process gas into a plasma processing chamber

(18; column 3, lines 20-47). The gas injector further comprises a gas injector body (56a/64,

Figure 1) sized to extend through a chamber wall (25) of the processing chamber.

As shown in Figure 1/1A, the distal end (64) of the gas injector body is exposed within the

processing chamber. Figure 1A shows that the gas injector body includes a plurality of angled

gas outlets (64) adapted to supply process gas into the processing chamber. Figures 1 and 1A

shows that the gas outlets (64, Figure 1,1A) of the gas injector body (56, Figure 1) are located at

an axial end surface (56) of the gas injector body.

Specifically, Li teaches a plurality of angled gas outlets (Figure 1A) extending at an acute angle

to the axial direction.

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It would have been obvious to one of ordinary skill in the art at the time the invention was made for Ishii to change the angle of a plurality of his gas outlets such that they extend at an acute

angle to the axial direction as taught by Li.

Motivation for Ishii to change the angle of a plurality of his gas outlets such that they extend at

an acute angle to the axial direction as taught by Li is to process larger area substrates (column 5,

lines 19-28).

Claims 28, 30-32, 35, 36, 39 and 40 rejected under 35 U.S.C. 103(a) as being 3.

unpatentable over Ishii (USPat. 5,685,942) and Li et al (USPat. 5,772,771), in view of McMillin

et al (USPat. 6,013,155). Ishii and Li are discussed above. However, Ishii and Li do not teach a

first O-ring seal in a surface of the flange for sealing against the outer surface of the chamber

wall. Ishii and Li do not teach a second O-ring seal on an outer surface of the gas injector body.

Ishii and Li further do not teach a gas injector for supplying process gas at sonic velocity.

McMillin teaches a gas injector (250, Figure 19b) supplying process gas, at sonic velocity

(column 7, lines 55-61), into a plasma processing chamber (140, Figure 2a). The gas injector

further comprises a gas injector body (250, Figure 19b) sized to extend through a chamber wall

(155) of the processing chamber. As shown in figure 19b, the distal end (220) of the of the gas

injector body is exposed within the processing chamber. Figure 19b shows that the gas injector

body includes a plurality of gas outlets (252, 254, 258) adapted to supply process gas into the

process chamber. Figure 19b shows that a gas outlet (258) of the gas injector body is located at

an axial end surface (258) of the gas injector body. McMillin also teaches a center gas outlet

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(258) extending in the axial direction and a plurality of angled gas outlets (254) extending at an acute angle to the axial direction. McMillin also teaches a closed distal end surface (surface housing outlet 258, Figure 19b) including gas outlets (254) that inject process gas at an acute

angle relative to a plane parallel to the distal end surface. McMillin also teaches at least one O-

ring seal (157; column 16, lines 11-30) providing a vacuum seal between the gas injector and the

chamber wall.

It would have been obvious to one of ordinary skill in the art at the time the invention was made

for Ishii to add an O-ring seal in a surface of the flange for sealing against the outer surface of

the chamber wall and to add a second O-ring seal on an outer surface of the gas injector body,

and to flow the process gas at sonic velocity as taught by McMillin.

Motivation for Ishii to add an O-ring seal in a surface of the flange for sealing against the outer

surface of the chamber wall and to add a second O-ring seal on an outer surface of the gas

injector body is to provide for vacuum integrity as taught by McMillin (column 16, lines 11-25).

Motivation for Ishii to optimize the flow the process gas to sonic velocity as taught by McMillin

is for preventing plasma penetration of the injectors as taught by McMillin (column 7, lines 55-

60). Further, it would be obvious to those of ordinary skill in the art to optimize the operation of

the claimed invention (In re Boesch, 617 F.2d 272, 205 USPQ 215 (CCPA 1980); In re

Hoeschele, 406 F.2d 1403, 160 USPQ 809 (CCPA 1969); Merck & Co. Inc. v. Biocraft

Laboratories Inc., 874 F.2d 804, 10 USPQ2d 1843 (Fed. Cir.), cert. denied, 493 U.S. 975 (1989); In re Kulling, 897 F.2d 1147, 14 USPQ2d 1056 (Fed. Cir. 1990), MPEP 2144.05).

Response to Arguments

4. Applicant's arguments filed December 10, 2002 have been fully considered but they are not persuasive. Applicant's arguments are directed to the amendment filed herewith. Applicant is directed to the body of the new claim rejections, necessitated by amendment, for a response to Applicant's arguments.

Conclusion

5. Applicant's amendment necessitated the new grounds of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Examiner Rudy Zervigon whose telephone number is (703) 305-

1351. The examiner can normally be reached on a Monday through Thursday schedule from 8am through 7pm. The official after final fax phone number for the 1763 art unit is (703) 872-9311. The official before final fax phone number for the 1763 art unit is (703) 872-9310. Any Inquiry of a general nature or relating to the status of this application or proceeding should be directed to the Chemical and Materials Engineering art unit receptionist at (703) 308-0661. If the examiner can not be reached please contact the examiner's supervisor, Gregory L. Mills, at (703) 308-1633.

JEFFRIE R. LUND
PRIMARY EXAMINER